

Docket No.: EHF 2001,0167 R



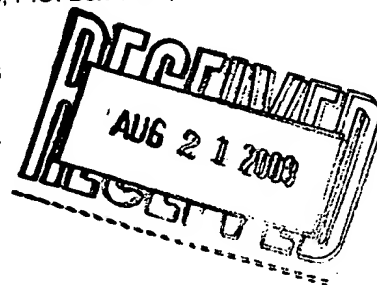
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By: [Signature]

Date: August 15, 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant : Norbert Benesch et al.
Applic. No. : 09/873,230
Filed : June 4, 2001
Title : Method and Device for Optically Monitoring Fabrication
Processes of Finely Structured Surfaces in a Semiconductor
Production
Art Unit : 2621

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AUG 20 2003

INFORMATION DISCLOSURE STATEMENT

Technology Center 2600

Hon. Commissioner for Patents

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

Japanese Patent Abstract JP 60 224 041 (Nakanishi et al.), dated November 8, 1985;

Korean Office Action dated June 23, 2003.

In accordance with 37 C.F.R. 1.97(e) the undersigned herewith states that each item of information contained in the information disclosure statement was first cited in a

communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

Respectfully submitted,



For Applicants

Mark P. Weichselbaum
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Date: August 15, 2003

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